Youngkee Eun

List of Publications by Year in descending order

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1163117 1125743 21 245 8 13 citations h-index g-index papers 21 21 21 252 docs citations times ranked citing authors all docs

#	Article	IF	CITATIONS
1	Aligned Carbon Nanotube Arrays for Degradationâ€Resistant, Intimate Contact in Micromechanical Devices. Advanced Materials, 2011, 23, 2231-2236.	21.0	59
2	Deformable Carbon Nanotube-Contact Pads for Inertial Microswitch to Extend Contact Time. IEEE Transactions on Industrial Electronics, 2012, 59, 4914-4920.	7.9	43
3	Integrated Carbon Nanotube Array as Dry Adhesive for Highâ€√Temperature Silicon Processing. Advanced Materials, 2011, 23, 4285-4289.	21.0	25
4	A highly sensitive flexible strain sensor based on the contact resistance change of carbon nanotube bundles. Nanotechnology, 2016, 27, 205502.	2.6	22
5	Development of MEMS Multi-Mode Electrostatic Energy Harvester Based on the SOI Process. Micromachines, 2017, 8, 51.	2.9	18
6	Using Confined Self-Adjusting Carbon Nanotube Arrays as High-Sensitivity Displacement Sensing Element. ACS Applied Materials & Samp; Interfaces, 2014, 6, 10181-10187.	8.0	13
7	Vertically aligned carbon nanotube arrays as vertical comb structures for electrostatic torsional actuator. Microelectronic Engineering, 2012, 98, 405-408.	2.4	12
8	Investigation of Interfacial Adhesion between the Top Ends of Carbon Nanotubes. ACS Applied Materials & Samp; Interfaces, 2014, 6, 6598-6605.	8.0	12
9	Low-Temperature Selective Growth of Tungsten Oxide Nanowires by Controlled Nanoscale Stress Induction. Scientific Reports, 2015, 5, 18265.	3.3	8
10	Thermally driven torsional micromirrors using pre-bent torsion bar for large static angular displacement. Journal of Micromechanics and Microengineering, 2009, 19, 045009.	2.6	7
11	Resonant Frequency Tuning of Torsional Microscanner by Mechanical Restriction using MEMS Actuator. , 2009, , .		5
12	Microswitch with self-assembled carbon nanotube arrays for high current density and reliable contact. , $2011, , .$		4
13	Angular vertical comb actuators assembled on-chip using in-plane electrothermal actuators and latching mechanisms. Sensors and Actuators A: Physical, 2011, 165, 94-100.	4.1	4
14	Micromachined Resonant Frequency Tuning Unit for Torsional Resonator. Micromachines, 2017, 8, 342.	2.9	4
15	Bidirectional Electrothermal Electromagnetic Torsional Microactuators. , 2009, , .		3
16	A novel accelerometer based on contact resistance of integrated carbon nanotubes. , 2011, , .		3
17	Reversible and Continuous Latching Using a Carbon Internanotube Interface. ACS Applied Materials & Samp; Interfaces, 2013, 5, 7465-7469.	8.0	3
18	Carbon Nanotubes: Integrated Carbon Nanotube Array as Dry Adhesive for Highâ€√emperature Silicon Processing (Adv. Mater. 37/2011). Advanced Materials, 2011, 23, 4208-4208.	21.0	0

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#	Article	IF	CITATIONS
19	Continuously latchable shuttle using carbon nanotubes on sidewall surfaces. , 2012, , .		O
20	Integrated carbon nanotube arrays for reliable contact in electromechanical memory device. , 2012, , .		O
21	Variable capacitor with switching mechanism for wide tuning range. , 2014, , .		O